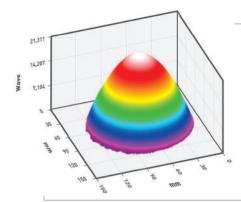


Interferometric solution for filters and coated optics testing at dedicated wavelengths

PHASICS is innovating in optical metrology with a new instrument able to measure both transmitted and reflected wavefront error (TWE/ RWE). Coated and uncoated optics can be qualified over a diameter of 5.1 inches (130 mm) at their working wavelengths.

Kaleo MultiWAVE is an advantageous alternative and costeffective solution to the purchase of several interferometers. The system offers a **measurement accuracy comparable to Fizeau interferometry.**

Kaleo MultiWAVE works at different wavelengths to perform qualification of optics and coatings at their working wavelengths.



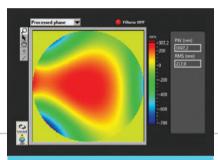
HIGH DYNAMIC RANGE

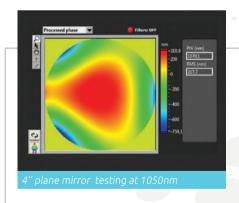
MEASUREMENT OF LARGE ABERRATIONS

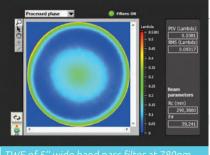
- More than 20λ of aberration can be measured with Kaleo MultiWAVE
- More dynamic range than a classical Fizeau interferometer

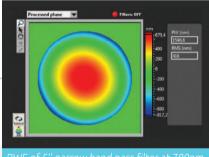
APPLICATIONS

- Coated optics and filters testing at real operating wavelengths
- High dynamics surface testing









ACHROMATIC SYSTEM

Same results at any wavelength

The instrument can be used at any wavelength to match the sample's operating wavelength

KEY FEATURES



Up to 8 wavelengths



High dynamic range



WFE & MTF measurement



Insensitive to vibration



Compatible with MetroPro & ISO

PHASICS - the phase control company | Kaleo MultiWAVE

SYSTEM			
Configuration	Double pass		
Measurement capability	RWE of reflective surfaces TWE of transparent optics		
Number of wavelengths per instrument	1 or 2 (standard), up to 8 (custom)		
Custom wavelengths	Any wavelength from 193 nm to 14 µm Including: UV: 266, 355, 405 nm VIS / NIR: 550, 625, 780, 940, 1050 nm SWIR / MWIR / LWIR: 1.55, 2.0, 3.39, 10.6 µm		
Clear aperture	5.1" (130 mm)		
Beam height	108 mm		
Alignment system	Live phase & Zernike coefficients display		
Polarization	Compatible with depolarizing optics		
Alignment FOV	+/- 2°		
Pupil focus range	+/- 2.5 m		
Dimensions	910 x 600 x 260 mm, 25 kg		
Vibration isolation	Not necessary		

PERFORMANCE ⁽¹⁾)
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RMS repeatability ⁽²⁾	$< 0.7 \text{ nm} (< \lambda / 900)$
Accuracy	80 nm PV ⁽³⁾
Dynamic range (defocus)	500 fringes (SFE = 150 μm)
Sample reflectivity range	~4% - 100%

- (1) On a 4" pupil size, with a 625 nm source
- (2) 36 sequential measurements are performed on a 4" reference mirror, each being averaged 16 times. A reference is defined as the average of all odd numbered measurements. RMS repeatability is then defined as the average RMS difference plus 2 times the standard deviation of the difference between even numbered measurements and the reference.
- (3) For a 1 μm PV defocus

MARKETS







Space & Defense



Automotive

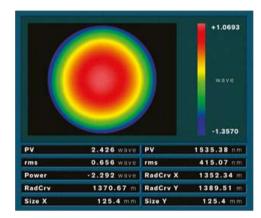
RESULTS SIMILAR TO FIZEAU INTERFEROMETRY

124.9 mm

FIZEAU INTERFEROMETER

+1.03085 -1.33661 PV 2.367 wave PV 1498.13 nm 0.637 wave rms 403,26 mm rms -2.213 wave RadCrv X 1367.01 m Power RadCrv 1399,81 m RadCrv Y 1434.33 m

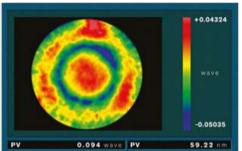
KALEO MULTIWAVE



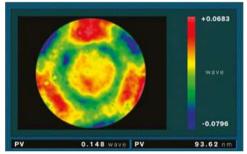
RESIDUAL raw power, ast, coma, spherical

Size X

RAW MEASUREMENT



124.9 mm Size Y



		FIZEAU	PHASICS
Diameter (mm)		124.9	125.4
RWE (nm PtV)		1498.13	1535.38
RWE (nm RMS) without PST/TLT/PWR		35.2	28.1
RWE (nm RMS) without ST/TLT/PWR/AST/CMA/SA		9.1	12.9
ISO 10110	SAG (fr)	5.13	5.04
	IRR (fr)	0.75	0.61
	RSI (fr)	0.34	0.23
	RMSt (fr)	1.477	1.459
	RMSi (fr)	0.129	0.103
	RMSa (fr)	0.085	0.059

